

Electronic Patent Application Fee Transmittal

Application Number:	10583976			
Filing Date:				
Title of Invention:	Method for setting plasma chamber having an adaptive plasma source, plasma etching method using the same and manufacturing method for adaptive plasma source			
First Named Inventor:	Yeong Su Song			
Filer:	Sungho Hong/Anita Coughlan			
Attorney Docket Number:	4913-0001			
Filed as Small Entity				
U.S. National Stage under 35 USC 371 Filing Fees				
Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
Basic Filing:				
Pages:				
Claims:				
Miscellaneous-Filing:				
Oath/decl > 30 mo. from priority date	2617	1	65	65
Petition:				
Patent-Appeals-and-Interference:				
Post-Allowance-and-Post-Issuance:				
Extension-of-Time:				

Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
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Total in USD (\$)				65